

## Supplementary Information for

### Mid-infrared InAs/InP quantum-dot lasers

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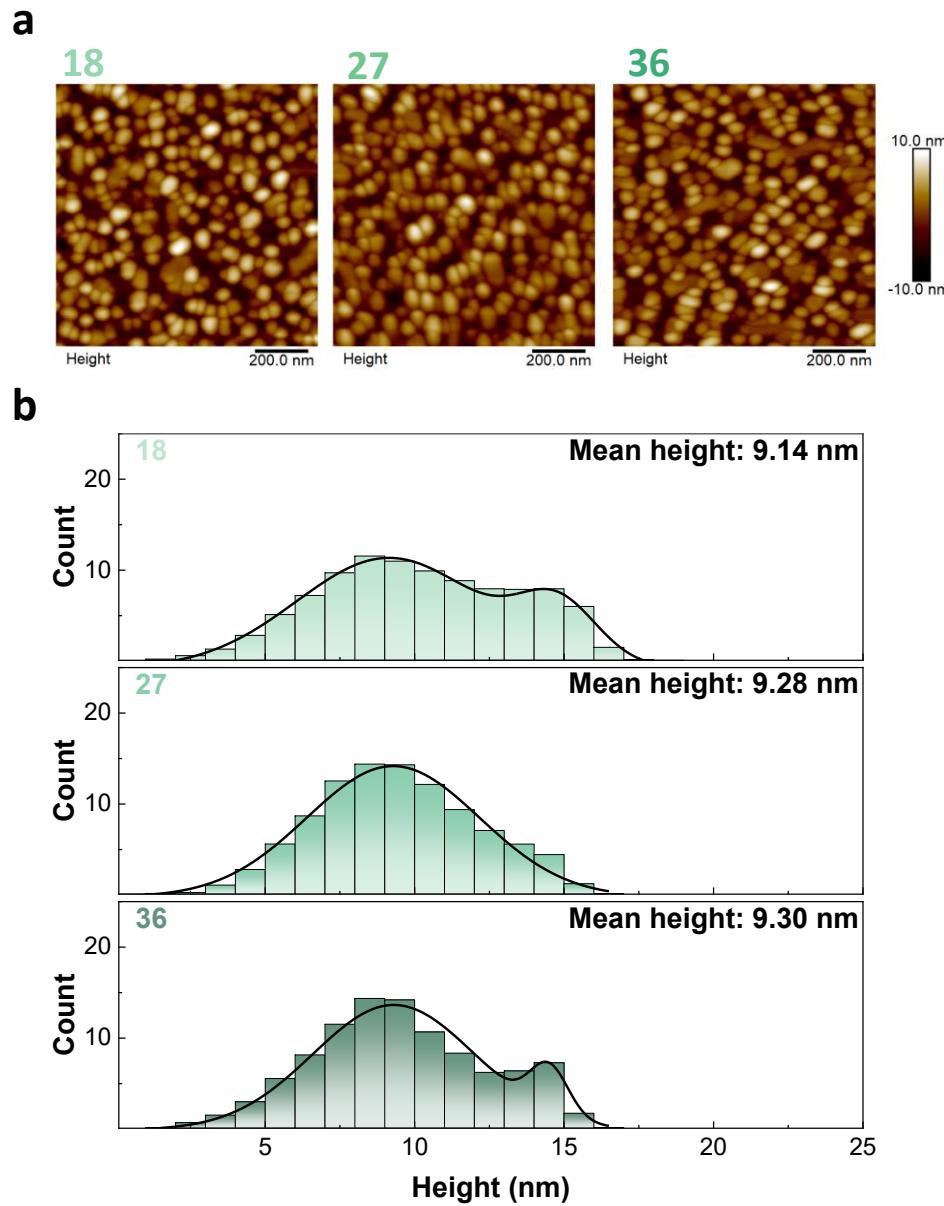
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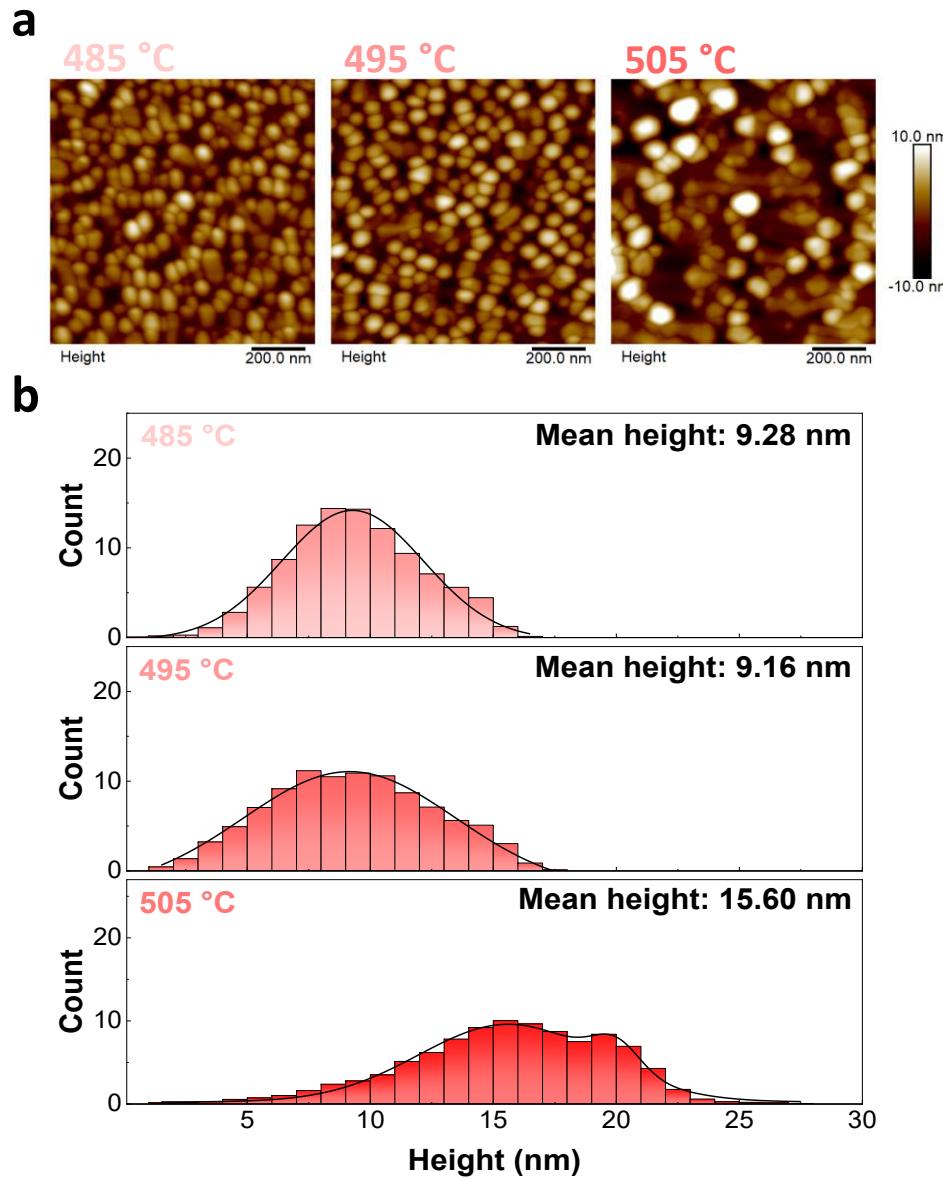
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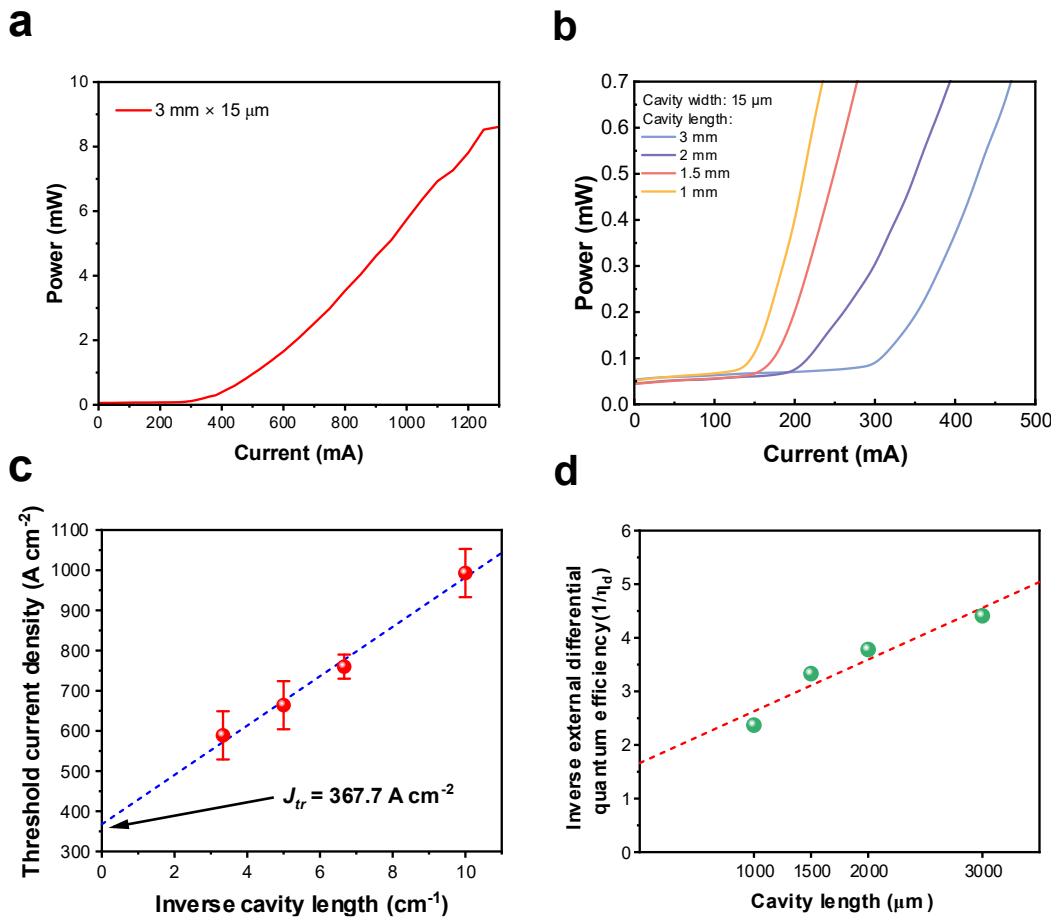
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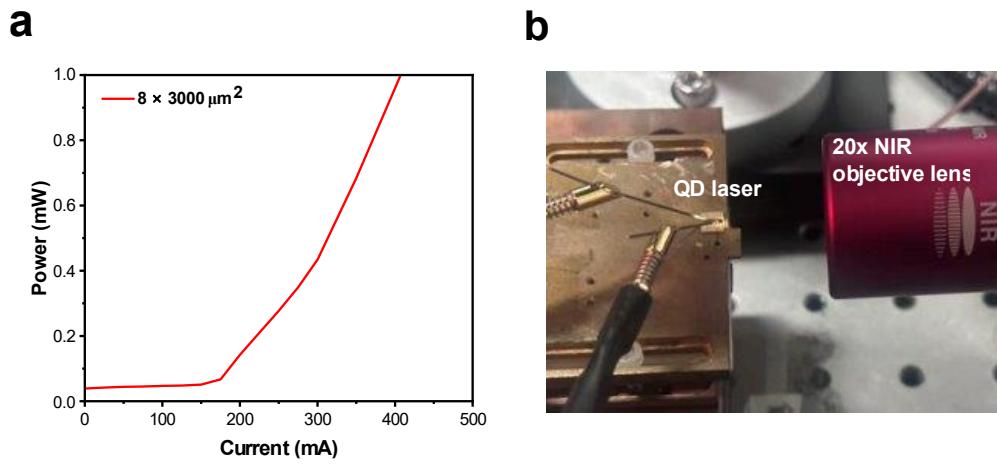
**Figure S1. Optimization of dot morphology of single-layer InAs/InP QDs under different V/III ratios. a**  $1 \times 1 \mu\text{m}^2$  AFM scans and **b** dot-height distribution for single-layer InAs/InP QDs grown at  $485^\circ\text{C}$  with 7.5 ML of InAs, under V/III ratios of 18, 27, and 36.



**Figure S2. Optimization of dot morphology of single-layer InAs/InP QDs at different QD growth temperatures. a**  $1 \times 1 \mu\text{m}^2$  AFM scans and **b** dot-height distribution for single-layer InAs/InP QDs with 7.5 ML of InAs and V/III ratio of 27, grown at temperatures of 485, 495, and 505 °C.



**Figure S3. Laser performance characterization with varied cavity lengths.** **a** Power versus current (L-I) curve for the 3 mm × 15 μm device at RT, showing a maximum power of 8.5 mW per facet. **b** RT L-I curves for InAs/InP QD lasers with a cavity width of 15 μm and varied cavity length from 1 to 3 mm. **c**  $J_{th}$  versus inverse cavity length for InAs/InP QD lasers, providing transparency current density ( $J_{tr}$ ). The error bars indicate the total observed range (minimum to maximum) of  $J_{th}$  for all measured devices at each cavity length. **d** Inverse external differential quantum efficiency ( $1/\eta_e$ ) versus cavity length for the InAs/InP QD lasers, where internal quantum efficiency ( $\eta_i$ ) of 60 % and internal loss ( $\alpha_i$ ) of  $6.7 \text{ cm}^{-1}$  were calculated.



**Figure S4. Far-field diffraction pattern measurement.** **a** L-I curve at RT for the  $3\text{ mm} \times 8\text{ }\mu\text{m}$  device used for far-field pattern measurement, showing a  $I_{\text{th}}$  of  $\sim 175\text{ mA}$ . **b** The set-up for far-field pattern measurement.